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740756-2431

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of)	
Osamu NAKAMURA et al) Attn:	Applications
Japanese Priority No.:	2001-034284)	Branch
Japanese Priority Date:	February 9, 2001)	
For: SEMICONDUCTOR DEVICE AND METHOD) Date:	February 5, 2002
METHOD FOR MANUFACTURING THE SAME)	



INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the reference(s) listed on the attached Form PTO-1449 be made of record in the above-identified application.

U.S. Patent No.: 5,643,826 is in the same family as Japanese Patent Application Laid-Open No.: 07-130652 and U.S. Patent No.: 6,255,195 is in the same family as Japanese Patent Application Laid-Open No.: 2000-260777.

At least some or all of the references listed on the attached Form PTO-1449 are discussed in the specification of the subject application.

Copies of the references are submitted herewith in accordance with 37 C.F.R. 1.98(a).

Respectfully submitted,

Jeffres/L. Costellia

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JLC/sas

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